

Title (en)
INTERFEROMETER SYSTEM

Title (de)
INTERFEROMETERSYSTEM

Title (fr)
SYSTEME D'INTERFEROMETRE

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Application
EP 02747900 A 20020618

Priority
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Abstract (en)
[origin: WO02103285A1] An interferometric measurement system capable of measuring tilt of a reflecting surface (26X, 26Y) with respect to a vertical axis (Z). The system preferably includes four laser beams (L1, L2, L3, L4) spaced at predetermined distances to measure distances between the measurement system and four locations on the reflecting surface. A controller (40) is also provided for receiving inputs from the measuring laser beams to mathematically determine a tilt of the location being measured.

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